



1763

SAM435-100/00645
Customer No. 24,118

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: CHO, DONG-IL)
SERIAL NO: 09/614,785)
FILED: 07/12/00)
FOR: SILICON ETCHING APPARATUS)
USING XeF₂)
ART UNIT: 1763)
EXAMINER: HASSANZADEH)

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3/20/02
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MAR 20 2002

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AMENDMENT

Director of United States Patent and Trademark Office
Box Non-Fee Amendment
Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated December 10, 2001, the Applicant requests the above-identified application be re-examined in view of the following amendments and remarks:

In the specification:

Page 4, line 10, change "Figs. 2 and 3" to - -Figs 2a-2d and 3a-3d- -.

In the claims:

Please amend claims 1 and 3 as follows:

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner of Patents, Washington, D.C. 20231, on March 5, 2002.

Amy Miles